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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Detlef Weber
Serial No. : 09/898,909
Filed : July 3, 2001
Title : METALLIZATION ARRANGEMENT FOR SEMICONDUCTOR STRUCTURE
AND CORRESPONDING FABRICATION METHOD

Art Unit : 2814
Examiner : P. Cao

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF JUNE 30, 2004

Please amend the above-identified application as follows:

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

August 27, 2004

Date of Deposit

Signature

Sharon Fernald

Sharon Fernald

Typed or Printed Name of Person Signing Certificate